

Abstracts

A Technique for Improving the Accuracy of Wafer Probe Measurements

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A technique has been developed to increase the accuracy of wafer probe measurements by identifying the calibration standards as "imperfect." Parasitic effects associated with each standard change their expected characteristics and can cause errors in the calibration data. A computer program is used with a network analyzer to determine the parasitic terms and minimize the measurement error.

[Return to main document.](#)